

Electron Beam Evaporation System

Model: SA-VKE1500Pro

SA-VKE1500Pro is a wafer-level fully-automatic electron-beam evaporation system. Equipped with an EFEM system, it delivers high-performance, stable and reliable operation alongside low-maintenance design to satisfy mass-production requirements.



Feature

- Low cost
- Lift-off
- Co-deposition
- High evaporation rate

Application

- Laser
- R&D
- Integrated circuit
- MEMS

Specifications:

Parameter	Descriptions
Number of Crucibles	8(max.)
Power Supply	10kW(max.)
Film thickness monitoring	Crystal oscillator controller
Ion Source	RF & Kaufman & Hall ion source
Fixture types	Dome & Knudsen & Planetary
Pumping System	Cryopump / magnetically levitated turbo-molecular pump + Dry mechanical pump
Coating Uniformity	±2%
Coating Repeatability	±2%
Uniform Deposition Area	12×Ø200 mm(max.)
Ultimate Vacuum	2E-5Pa
Vacuum Measurement	Full-range vacuum gauge
Temperature Control Range	RT~200℃
Space Requirements(L×W×H,m)	8.5×5.5×3.3

Principle:

